

Commissioning of a New Solder Bumping Process for the Pixel Upgrade

Summer Student Programme 2013

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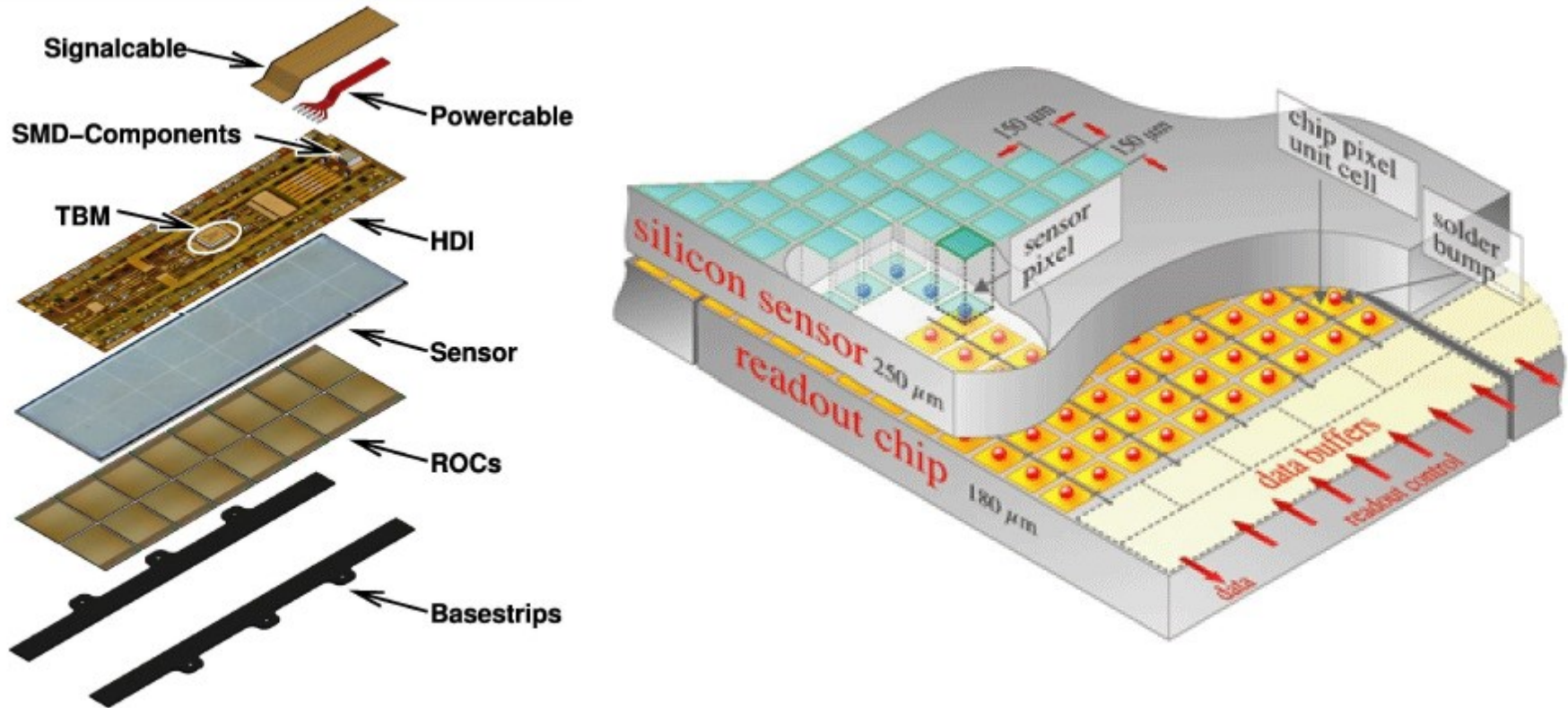
DESY CMS Summer Student Talks
Hamburg, Sep 2nd 2013

> Introduction

- > Bumping Process
- > Inspection Methods
- > Reflow Process
- > Conclusions



Structure of the Pixel Detector Module



Pictures from „CMS Pixel Detector Upgrade, Daniel Pitzl, DESY Instrumentation Seminar 16.9.2011“

Agenda

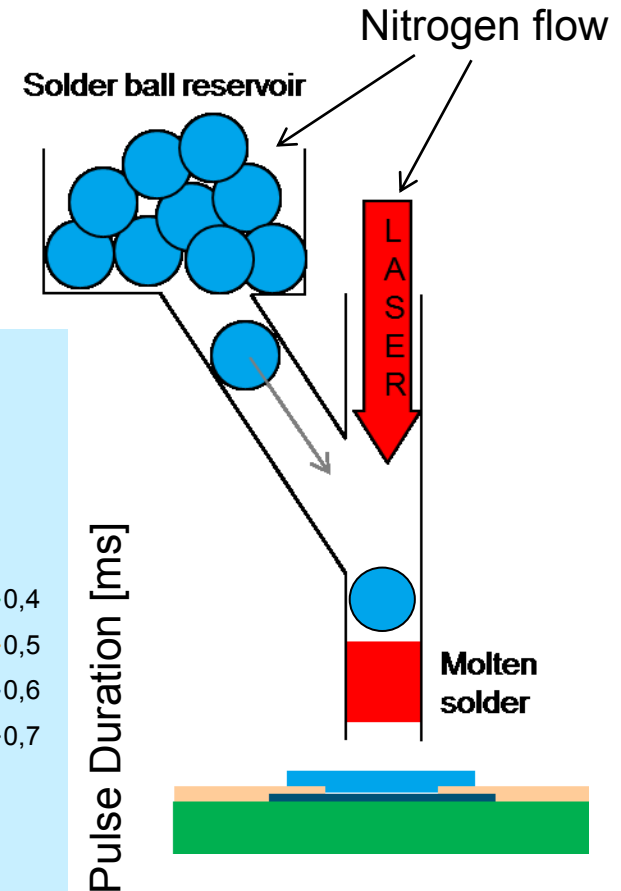
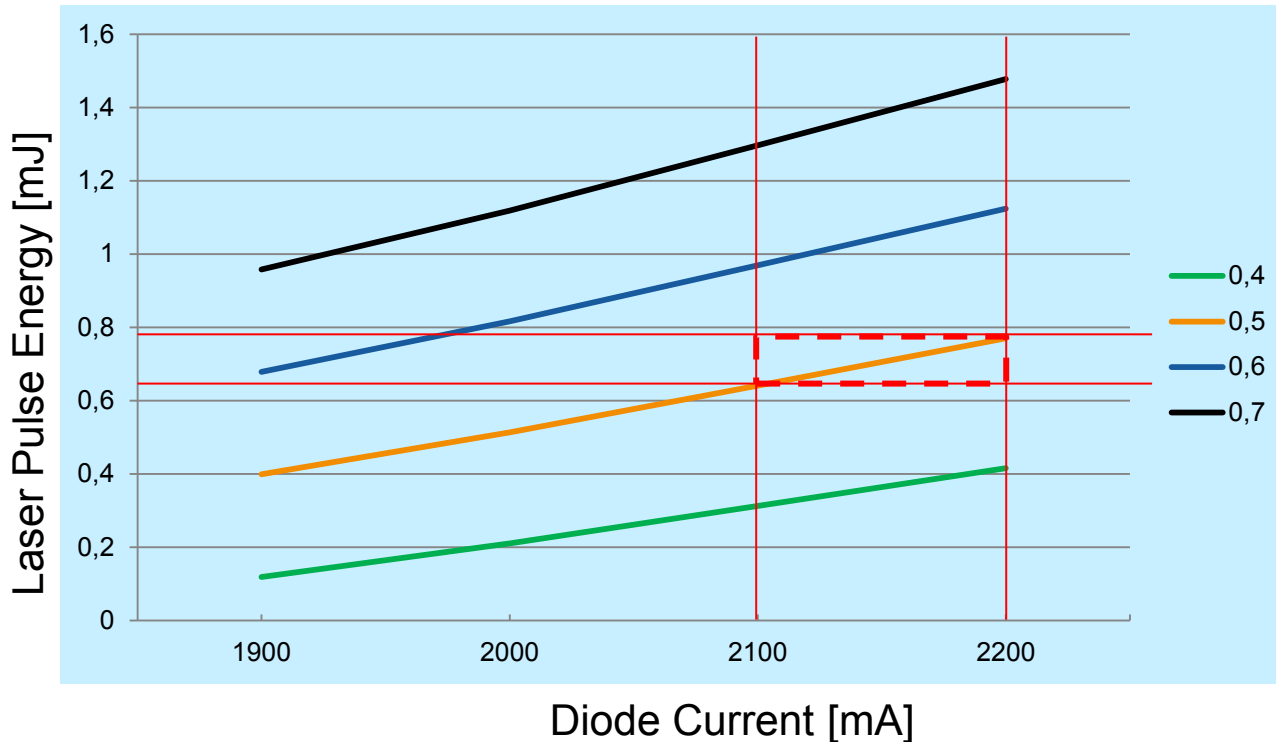
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Bump Bonding Process

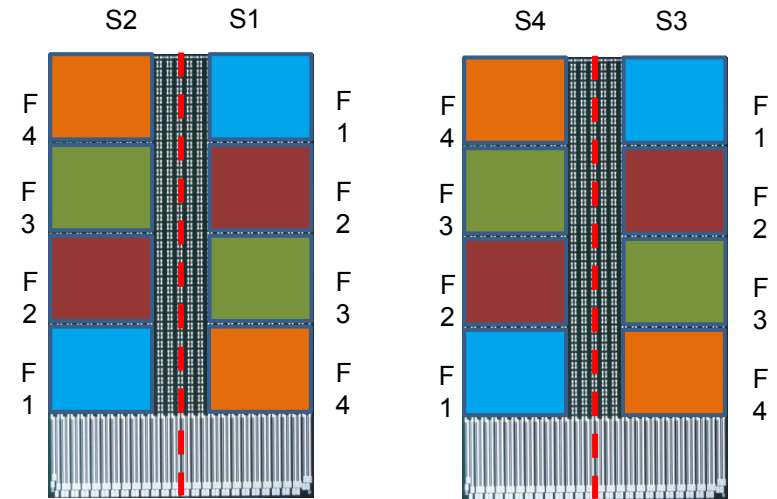
➤ Process speed is influenced by:

- Pulse length
- Pulse power
- Feeder pressure



Bumping Parameter Settings Overview

- > Number of columns = 20
- > Number of rows per field = 19
- > Number of bumps per field = 380
- > One bump free row for field separation



	160 mbar		180 mbar	
	Sample 1	Sample 2	Sample 3	Sample 4
Constant Parameter	2100 mA	0.5 ms	2100 mA	0.5 ms
Field 1	0.4 ms	1900 mA	0.4 ms	1900 mA
Field 2	0.6 ms	2000 mA	0.5 ms	2000 mA
Field 3	0.7 ms	2200 mA	0.6 ms	2200 mA
Field 4	0.5 ms	2300 mA	0.7 ms	2300 mA
ΔE	0.33 mJ	0.12 mJ	0.33 mJ	0.12 mJ

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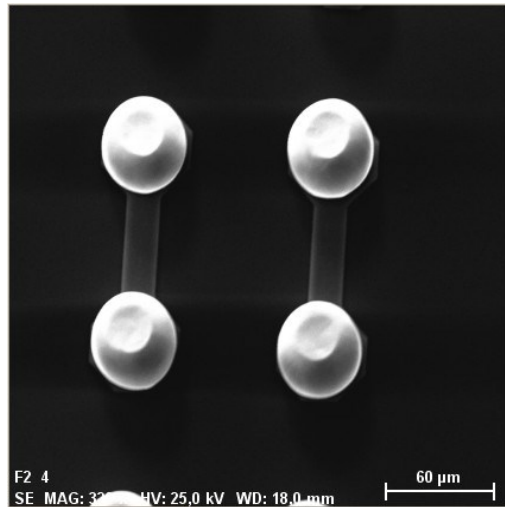
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Inspections Methods

Example: sample 4 field 2

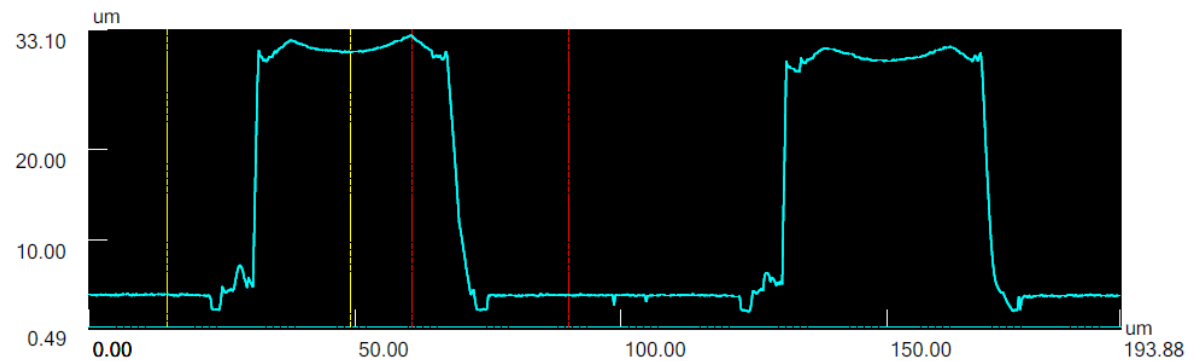
Scanning Electron Microscope



Optical Microscope Picture of cross-section



Scanning Laser Microscope
(dimensions in μm)



Results from the Bump Bonding

- > Interactions between pads and bumps are negligibles
- > Average speed: 4.8 Hz
- > Optimal parameters are:
 - 2100 mA Laser diode current 0.5 ms Laser pulse lenght (0.64 mJ)
 - Lower energy limit to have good shaped bumps
 - „Saturation“ of the bump shape after the optimal energy

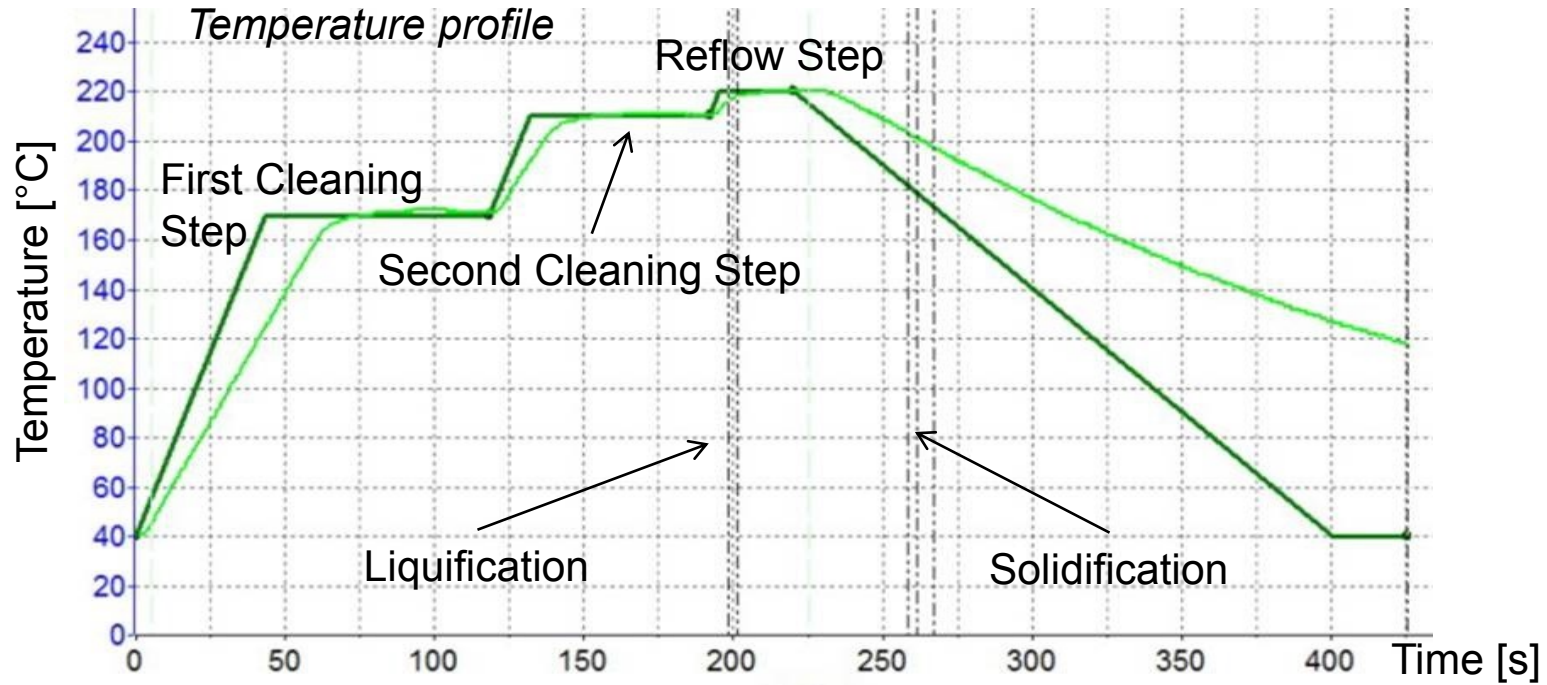


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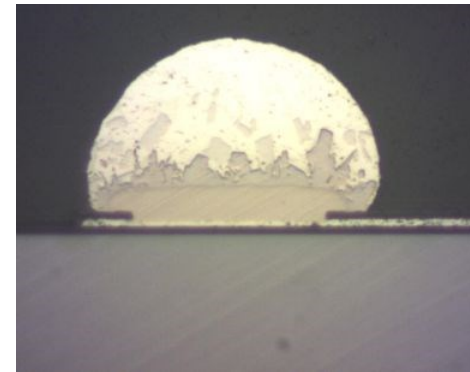
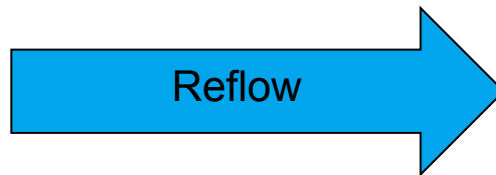
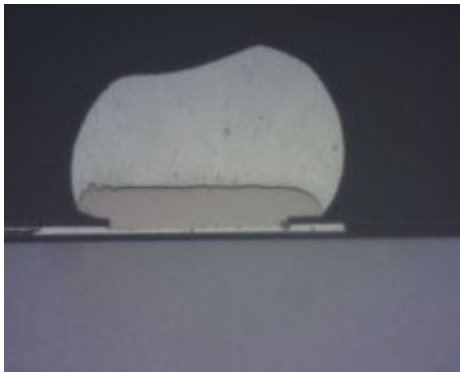
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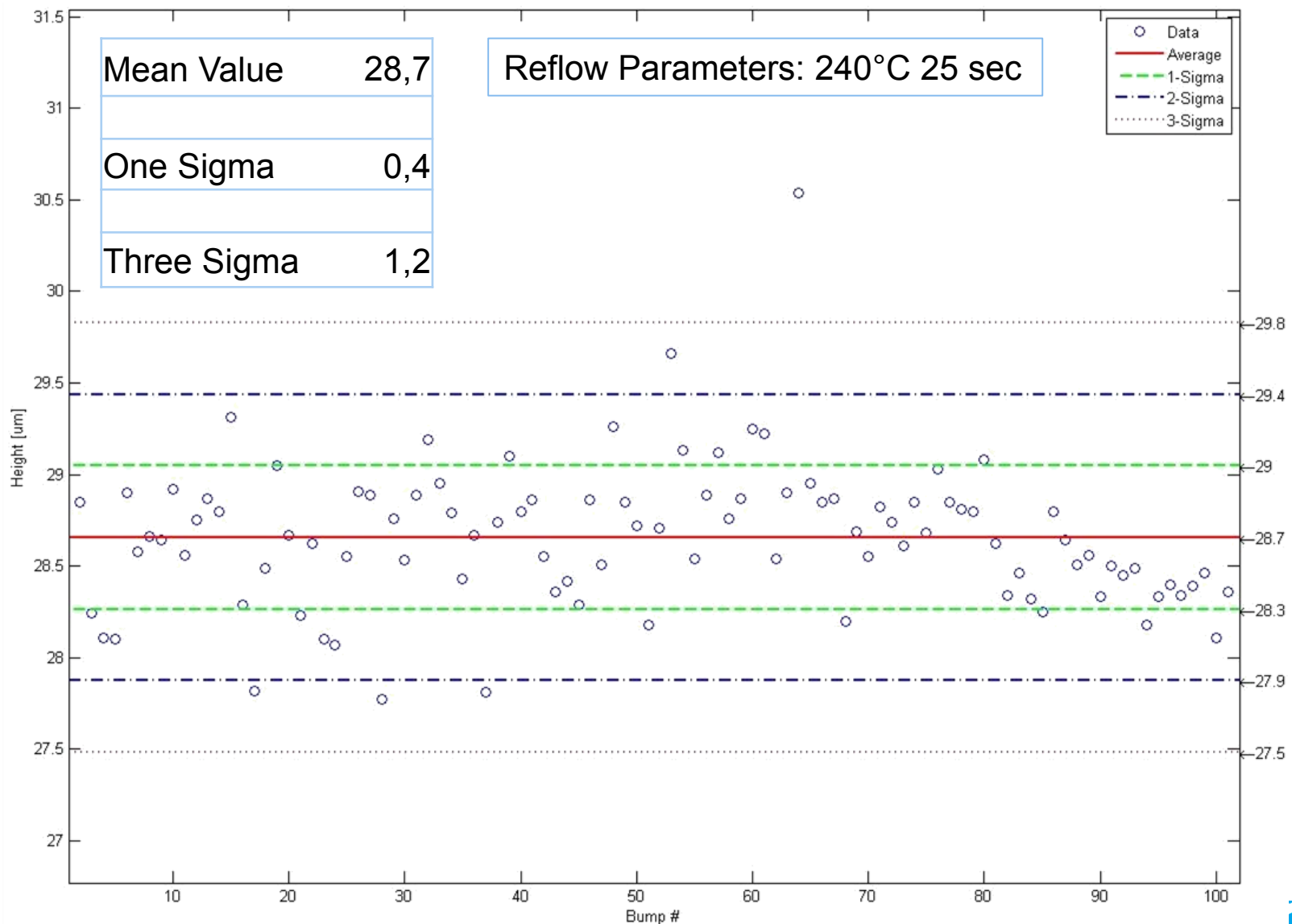
Reflow Process and Scans



Cross-section view before and after the reflow



Height Statistic Analysis after the Reflow



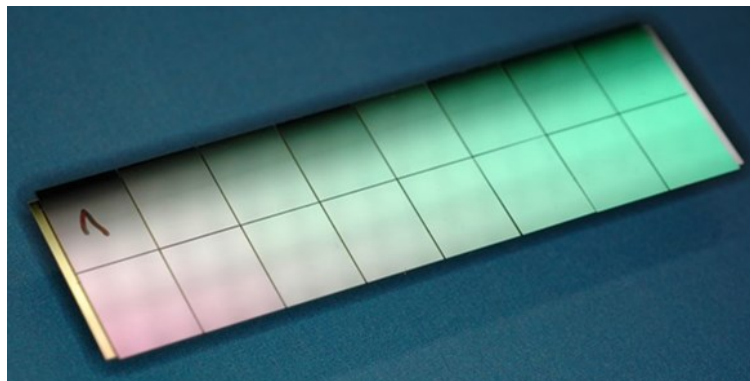
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Results and Future Developments

- > Bump Bonding Optimal Parameters: 2100 mA 0.5 ms 180 mbar
- > Reflow Optimal Parameters: 220°C 10 s
- > Improvements of the reflow process
 - Studies about interactions between bump and pad
 1. Temperature dependance
 2. Materials dependance
 3. Duration of the treatment
 4. Speed of the process
 5. Dimensions
 6. ...
- > Development of the flip chip bonding process



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Thanks for your attention!

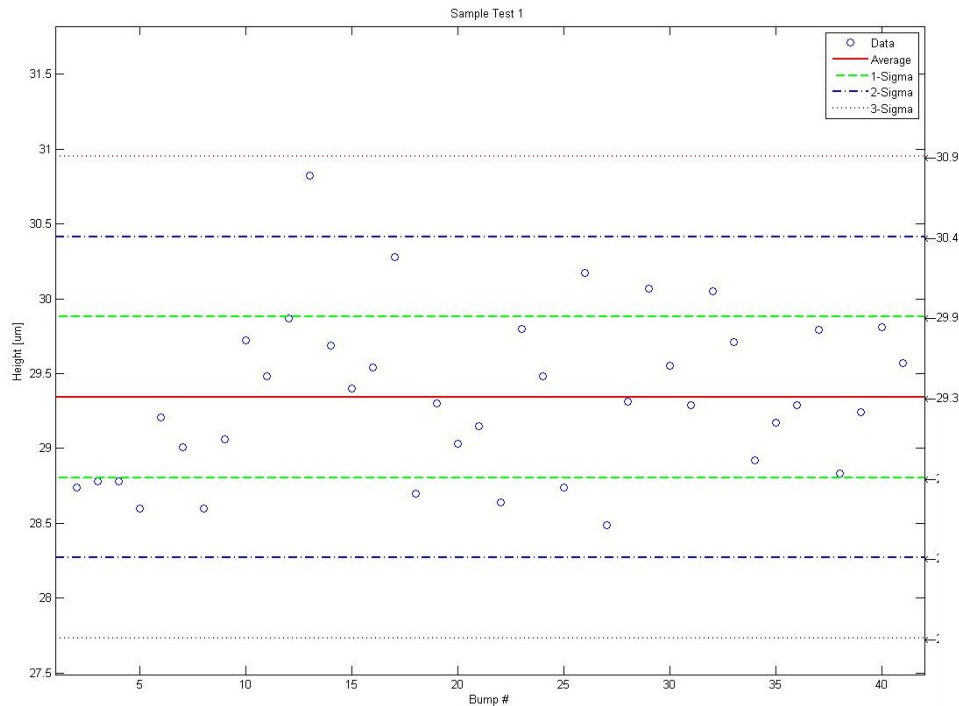
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Back Up



Reflow Parameters



Reflow Parameters: 220°C 25 seconds

mean value r	29,3
one sigma	0,5
three sigma	1,5

mean value r	29,8
one sigma	0,5
three sigma	1,5

Reflow Parameters: 220°C 10 seconds

